

PATENT Customer No. 22,852 Attorney Docket No. 04329.2566

TECHNOLOGY CENTER 2800

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE Group Art Unit: 2823 May 102

Examiner: M. Estrada

In re Application of:

SHINICHI ITO et al. >

Application No.: 09/842,403

Filed: April 26, 2001

FILM FORMATION METHOD, SEMICONDUCTOR

ELEMENT AND METHOD THEREOF, AND METHOD OF MANUFACTURING A DISK-

SHAPED STORAGE MEDIUM

Commissioner for Patents and Trademarks

Washington, DC 20231

Sir:

RESPONSE TO RESTRICTION REQUIREMENT

In a restriction requirement dated August 28, 2002, the Examiner required restriction under 35 U.S.C. § 121 between:

Group I - Claims 1-18, 20, 22, and 23, and

Group II - Claims 19 and 21.

Applicants provisionally elect to prosecute Group I, claims 1-18, 20, 22, and 23, drawn to a method of making a semiconductor device, without traverse.

Please grant any extensions of time required to enter this response and charge any additional required fees to our Deposit Account No. 06-0916.

Respectfully submitted,

FINNEGAN, HENDERSON, FARABOW,

GARRETT & DUNNER, L.L.P.

Dated: Sept 27, 2002

By: Richard V. Burgujian

Reg. No. 31,744

FINNEGAN FARABOW GARRETT & DUNNER LLP

1300 I Street, NW Washington, DC 20005 202.408.4000 Fax 202.408.4400 www.finnegan.com